

Electronic Patent Application Fee Transmittal

Application Number:	10586788			
Filing Date:	02-Sep-2008			
Title of Invention:	Plasma Excited Chemical Vapor Deposition Method Silicon/Oxygen/ Nitrogen-Containing-Material and Layered Assembly			
First Named Inventor/Applicant Name:	Zvonimir Gabric			
Filer:	Ira Stuart Matsil/Julie Russell			
Attorney Docket Number:	2006 VJ 33543 US			
Filed as Large Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Submission- Information Disclosure Stmt	1806	1	180	180
Total in USD (\$)				180